

3/26/04

INFORMATION DISCLOSURE CITATION PTO-1449	ATTY. DOCKET NO. P132-US	SERIAL NO. 10/811449 Not Yet Assigned
	APPLICANT Jim Dunphy, et al.	
	FILING DATE Herewith	GROUP Not Yet Assigned

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
Dle	U.S Pub App No. 2003/0002019	1/2/03	Miller			
	U.S Pub App No. 2002/0056898	5/16/02	Lopes, et al.			
	U.S Pub App No. 2002/0063322	5/30/02	Robbins, et al.			
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Dle	5,512,374	4/30/96	Wallace, et al.			

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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Dle	"Lubrication of Digital Micromirror Devices" Henck, Tribology Letters 3 (1997) 239-247						
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INFORMATION DISCLOSURE CITATION		ATTY. DOCKET NO. P132-US	SERIAL NO. 10/811,449
APR 28 2005 PTO-1449		APPLICANT Dunphy, et al.	
SHEET 1 OF 2		FILING DATE 3/26/04	GROUP Not Yet Assigned

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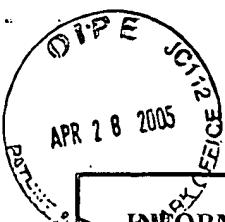
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	W. Robert Ashurst et al., VAPOR PHASE ANTI-STICKTION COATINGS FOR MEMS, Pgs 1-6.
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INFORMATION DISCLOSURE CITATION PTO-1449 SHEET 2 OF 2		ATTY. DOCKET NO. P132-US		SERIAL NO. 10/811,449		
		APPLICANT Dunphy, et al.				
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Dle	2004/0012838	1/22/04	Huibers			
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